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Editorial ICCPS 11

This supplementary issue compiles a number of key papers presented at the 11th International Conference on Ceramic Processing Science (ICCPS-11), which was held at the Campus Science City of ETH Zurich, Switzerland from August 29th to September 1st in 2010. The meeting was chaired by Ludwig Gauckler, and co-chaired by Gary L. Messing and Kunihito Koumoto. This symposium is held every 2–3 years and has rotated between the United States, Japan, and Germany as a result of it being initially organized by Professors Hans Hausner, Shin-ichi Hirano, and Gary L. Messing. The 11th conference was attended by more than 400 scientists, engineers, and practitioners. It attracted more than 40 of the most prominent scientists in the fields giving plenary and invited talks about new ceramic compositions, processing, properties and related microstructures. In total 164 oral contributions and 150 poster contributions covered the latest findings and developments. Extensive research on nano effects in ceramics has uncovered many interesting and promising materials properties for novel applications in electronics, photonics, and biology. Ceramic thin films from solution chemistry but also processed



via the gas phase and physical processes and their properties got increased attention.

This special issue contains a series of original contributions of the attendees. From the 214 conference contributions 17% are published in this issue allowing to harvest some of the benefits of this conference as well as to identify promising future paths between fundamental research and applications.

We would like to acknowledge the hard work of the symposium participants for meeting the numerous deadlines to enable the publication of this special issue.

As editor of this special issue, I sincerely thank Prof. R.I. Todd from Dept. of Materials, University of Oxford, Senior Editor of this journal, for making this special edition a reality. My sincere gratitude also goes to Anja Bieberle, Jennifer Rupp, Julia-Maria Martynczuk, André Studart, Markus Niederberger, Lorenz Bonderer, Rodrigo Moreno and Urs Gonzenbach, who handled the refereeing as guiding editors, as well as all contributors and all reviewers of these manuscripts.

Enjoy the papers assembled here and we hope to see you at the 12th International Conference on Ceramic Processing Science in the USA.

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